

FORM PTO-1449 (Modified) LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)			Attorney Docket No.: 18419-008210US		Application No.:	
			Applicant: Sien G. Kang et al.			
			Filing Date: Herewith		Group: Unassigned	

Reference Designation			U.S. PATENT DOCUMENTS			Page 1
Examiner Initial	Document No.	Date	Name	Class	Sub-class	Filing Date (If Appropriate)
<u>SL</u> AA	3,964,957	6/22/76	Walsh	156	345	
<u> </u> AB	4,495,219	01/22/85	Kato et al.	427	82	
<u> </u> AC	4,906,594	03/06/90	Yoneda et al.	437	228	
<u> </u> AD	5,198,071	03/30/93	Scudder et al.	156	625	
<u> </u> AE	5,198,371	03/30/93	Li	437	11	
<u> </u> AF	5,213,986	05/25/93	Pinker et al.	437	20	
<u> </u> AG	5,374,564	12/20/94	Bruel	437	24	
<u> </u> AH	5,686,980	11/11/97	Hirayama et al.	349	110	
<u> </u> AI	5,869,387	02/09/99	Sato et al.	438	459	
<u>LA</u> AJ	6,008,128	12/28/99	Habuka et al.	438	695	
<u> </u> AK						
<u> </u> AL						

FOREIGN PATENT DOCUMENTS						
	Document No.	Date	Country	Class	Sub-class	Translation (Yes/No)
<u> </u> AM						
<u> </u> AN						
<u> </u> AO						
<u> </u> AP						
<u> </u> AQ						
<u> </u> AP						

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)	
<u> </u> AS	Centura Epi "Epitaxial Deposition Chamber Specifications" Brochure, Applied Materials, March 1994
<u> </u> AT	EPI CENTURA Systems Specification Brochure, Applied Materials, October 1996
<u> </u> AU	
<u> </u> AV	
<u> </u> AW	

EXAMINER	DATE CONSIDERED <u>2/18/2002</u>
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.